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Sommario/riassunto

This comprehensive manual provides practical guidance and insights into Microelectromechanical Systems (MEMS), with a focus on microfluidic device design, fabrication techniques, and simulation methodologies. Edited by Sanket Goel, the book explores various advanced topics such as additive manufacturing, laser processing, electrode fabrication, and spectroscopic analysis, supported by real-world applications. It includes contributions from multiple experts, offering detailed procedures, prerequisites, and experimental setups for designing and fabricating MEMS devices. Designed for researchers, engineers, and professionals working in sensor technology and microsystems, the manual serves as a valuable resource for mastering modern MEMS practices and methodologies.